Title (en)

Method and apparatus for forming films.

Title (de)

Verfahren und Vorrichtung zur Herstellung von Filmen.

Title (fr)

Procédé et appareil pour la formation de films.

Publication

EP 0190051 A2 19860806 (EN)

Application

EP 86300646 A 19860130

Priority

JP 1581985 A 19850130

Abstract (en)

In a method and apparatus for forming a film wherein ions formed by electric discharge are caused to sputter a target electrode (7), and atoms emitted by the target electrode (7) as a result of sputtering are deposited on the surface of a substrate (9) to form the film, light is projected upon the surface of the substrate (9) to activate the same.

IPC 1-7

C23C 14/34

IPC 8 full level

H01L 21/31 (2006.01); **C23C 14/22** (2006.01); **C23C 14/34** (2006.01); **H01L 21/203** (2006.01)

CPC (source: EP)

C23C 14/22 (2013.01); **C23C 14/34** (2013.01); **C23C 14/3435** (2013.01)

Cited by

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EP 0190051 A2 19860806; **EP 0190051 A3 19870520**; **EP 0190051 B1 19920325**; DE 3684489 D1 19920430; JP S61174726 A 19860806

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